

EV550717305



Inventor: **Brian E. Cron**

Title: **Methods for Conditioning Surfaces of Polishing Pads After
Chemical-Mechanical Polishing**

Assignee: **Micron Technology, Inc.**

Serial No.: **10/705,371**

Filed: **November 10, 2003 [RCE Filed Herewith]**

INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

The attached Form PTO-1449 is submitted in compliance with 37 CFR §1.56. Pursuant to FEDERAL REGISTER, Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. No admission is made regarding whether the listed reference is prior art.

Citation of this reference is respectfully requested.


Respectfully submitted,

Date: 6/2/05

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2430		SERIAL NO. 10/705,371	
 LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Brian E. Cron			
				FILING DATE Nov. 10, 2003 [RCE filed herewith]		GROUP 3723	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,332,835 B1	12/01	Nishimura et al.			
	AB						
	AC						
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	AF						
	AG						
	AH						
	AI						
	AJ						
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FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AM						
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
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